

<b>Notice of Allowability</b>	<b>Application No.</b>	<b>Applicant(s)</b>	
	10/759,718	JANGBARWALA, JUZER	
	<b>Examiner</b>	<b>Art Unit</b>	
	Ngoc-Yen M. Nguyen	1793	

**-- The MAILING DATE of this communication appears on the cover sheet with the correspondence address--**

All claims being allowable, PROSECUTION ON THE MERITS IS (OR REMAINS) CLOSED in this application. If not included herewith (or previously mailed), a Notice of Allowance (PTOL-85) or other appropriate communication will be mailed in due course. **THIS NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RIGHTS.** This application is subject to withdrawal from issue at the initiative of the Office or upon petition by the applicant. See 37 CFR 1.313 and MPEP 1308.

1. ☒ This communication is responsive to July 14, 2008.
2. ☒ The allowed claim(s) is/are 1-3, 7 and 8.
3. ☐ Acknowledgment is made of a claim for foreign priority under 35 U.S.C. § 119(a)-(d) or (f).
  - a) ☐ All    b) ☐ Some\*    c) ☐ None    of the:
    1. ☐ Certified copies of the priority documents have been received.
    2. ☐ Certified copies of the priority documents have been received in Application No. \_\_\_\_\_.
    3. ☐ Copies of the certified copies of the priority documents have been received in this national stage application from the International Bureau (PCT Rule 17.2(a)).

\* Certified copies not received: \_\_\_\_\_.

Applicant has THREE MONTHS FROM THE "MAILING DATE" of this communication to file a reply complying with the requirements noted below. Failure to timely comply will result in ABANDONMENT of this application.

**THIS THREE-MONTH PERIOD IS NOT EXTENDABLE.**

4. ☐ A SUBSTITUTE OATH OR DECLARATION must be submitted. Note the attached EXAMINER'S AMENDMENT or NOTICE OF INFORMAL PATENT APPLICATION (PTO-152) which gives reason(s) why the oath or declaration is deficient.
5. ☐ CORRECTED DRAWINGS ( as "replacement sheets") must be submitted.
  - (a) ☐ including changes required by the Notice of Draftsperson's Patent Drawing Review ( PTO-948) attached
    - 1) ☐ hereto or 2) ☐ to Paper No./Mail Date \_\_\_\_\_.
  - (b) ☐ including changes required by the attached Examiner's Amendment / Comment or in the Office action of Paper No./Mail Date \_\_\_\_\_.

**Identifying indicia such as the application number (see 37 CFR 1.84(c)) should be written on the drawings in the front (not the back) of each sheet. Replacement sheet(s) should be labeled as such in the header according to 37 CFR 1.121(d).**
6. ☐ DEPOSIT OF and/or INFORMATION about the deposit of BIOLOGICAL MATERIAL must be submitted. Note the attached Examiner's comment regarding REQUIREMENT FOR THE DEPOSIT OF BIOLOGICAL MATERIAL.

**Attachment(s)**

- |   |  |
|---|--|
| <ol style="list-style-type: none"> <li>1. <input type="checkbox"/> Notice of References Cited (PTO-892)</li> <li>2. <input type="checkbox"/> Notice of Draftsperson's Patent Drawing Review (PTO-948)</li> <li>3. <input checked="" type="checkbox"/> Information Disclosure Statements (PTO/SB/08),<br/>Paper No./Mail Date <u>7/14/08</u></li> <li>4. <input type="checkbox"/> Examiner's Comment Regarding Requirement for Deposit of Biological Material</li> </ol> | <ol style="list-style-type: none"> <li>5. <input type="checkbox"/> Notice of Informal Patent Application</li> <li>6. <input checked="" type="checkbox"/> Interview Summary (PTO-413),<br/>Paper No./Mail Date _____.</li> <li>7. <input checked="" type="checkbox"/> Examiner's Amendment/Comment</li> <li>8. <input checked="" type="checkbox"/> Examiner's Statement of Reasons for Allowance</li> <li>9. <input type="checkbox"/> Other _____.</li> </ol> |
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### EXAMINER'S AMENDMENT

An examiner's amendment to the record appears below. Should the changes and/or additions be unacceptable to applicant, an amendment may be filed as provided by 37 CFR 1.312. To ensure consideration of such an amendment, it MUST be submitted no later than the payment of the issue fee.

Authorization for this examiner's amendment was given in a telephone interview with Ms. Nicholes on September 12, 2008.

The application has been amended as follows:

1. (currently amended) A method for removing fluorine gas from a selected environment, comprising the steps of:

(a) contacting the fluorine gas from the environment with a selected quantity of water in an ion-exchange resin, thereby to generate an acidic solution of hydrofluoric acid; ~~and~~

(b) contacting said acidic solution of hydrofluoric acid with the ion-exchange resin having an active state operative to exchange selected ions therein for fluoride ions in said acidic solution when in contact therewith~~[[,]]~~ ; and

~~wherein said ion-exchange resin is capable of chemically shifting between said active state and an exhausted state operative to exchange the fluoride ions in said ion-exchange resin for the selected ions contained in a regenerant solution when in contact therewith, and including the step of~~

(c) regenerating said ion-exchange resin when it becomes exhausted by contacting said ion-exchange resin with the a regenerant solution to exchange the fluoride ions in said ion-exchange resin for the selected ions contained in the regenerant

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solution thereby ~~to form~~ forming a selected regenerant waste product containing the fluoride ions, and

wherein said regenerant solution is selected from the group consisting of ammonium hydroxide solution, waste ammonium hydroxide solution, and any combination thereof.

2. (currently amended) The method according to claim 1 wherein the regenerant solution is a waste ammonium hydroxide solution.

3. (previously presented) The method according to claim 1 wherein the waste ammonium hydroxide solution is generated from one or more processes associated with the fluorine gas from a selected environment.

Claims 4-6 (cancelled)

7. (previously presented) The method according to claim 1 wherein in step (a) ~~comprising the step of providing~~ a vacuum pump is used to supply ~~wherein the step of~~ ~~contacting the fluorine gas from the semiconductor process to the environment~~ with a the selected quantity of water in the ion-exchange resin ~~comprises exhausting the fluorine gas from the vacuum pump into the selected quantity of water.~~

8. (previously presented) The method according to claim 2 wherein the waste ammonium hydroxide solution is generated from a chemical-mechanical polishing ("CMP") process.

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The following is an examiner's statement of reasons for allowance: the prior art does not disclose or suggest the reaction between a fluorine gas and water that is contained in an anion-exchange resin to form an acidic solution of hydrofluoric acid and exchanging selected ions in the ion-exchange resin for the fluoride ions in the acidic solution.

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

Any inquiry concerning this communication or earlier communications from the examiner should be directed to Ngoc-Yen M. Nguyen whose telephone number is (571) 272-1356. The examiner can normally be reached on Part time schedule.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Stanley Silverman can be reached on (571) 272-1358. The fax phone number for the organization where this application or proceeding is assigned is 571-273-8300.

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Information regarding the status of an application may be obtained from the Patent Application Information Retrieval (PAIR) system. Status information for published applications may be obtained from either Private PAIR or Public PAIR. Status information for unpublished applications is available through Private PAIR only. For more information about the PAIR system, see <http://pair-direct.uspto.gov>. Should you have questions on access to the Private PAIR system, contact the Electronic Business Center (EBC) at 866-217-9197 (toll-free). If you would like assistance from a USPTO Customer Service Representative or access to the automated information system, call 800-786-9199 (IN USA OR CANADA) or 571-272-1000.

/Ngoc-Yen M. Nguyen/  
Primary Examiner, Art Unit 1793

nmn  
September 19, 2008